

Image



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In application of : **Confirmation No. 8728**
Norio KIMURA et al. : Docket No. 2000-1761A
Serial No. 09/742,386 : Group Art Unit 1763
Filed December 22, 2000 : Examiner Sylvia MacArthur

APPARATUS AND METHOD FOR
PROCESSING SEMICONDUCTOR
SUBSTRATE

ELECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of December 8, 2003, Applicants in the above-referenced U.S. patent application hereby elect the invention of group I corresponding to claims 1-45 and 60-72 without traverse.

An early and favorable action on the merits is requested.

Respectfully submitted,

Norio KIMURA et al.

By: _____

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